

L Number	Hits	Search Text	DB	Time stamp
1	0	"10655850"	USPAT; US-PGPUB	2004/10/31 11:33
2	0	10/655850	USPAT; US-PGPUB	2004/10/31 11:34
-	444	702/82-84.ccls.	USPAT; US-PGPUB	2004/10/31 10:47
-	469	700/109,110.ccls.	USPAT; US-PGPUB	2004/10/30 09:29
-	833	702/82-84.ccls. or 700/109,110.ccls.	USPAT; US-PGPUB	2004/10/30 09:29
-	926	700/121.ccls. not 700/109,110.ccls.	USPAT; US-PGPUB	2004/10/30 10:13
-	116	(700/121.ccls. not 700/109,110.ccls.) and (determin\$3 same yield)	USPAT; US-PGPUB	2004/10/30 10:21
-	327	(700/121.ccls. not 700/109,110.ccls.) and yield	USPAT; US-PGPUB	2004/10/30 10:21
-	211	((700/121.ccls. not 700/109,110.ccls.) and yield) not ((700/121.ccls. not 700/109,110.ccls.) and (determin\$3 same yield))	USPAT; US-PGPUB	2004/10/30 10:25
-	301	determin\$3 with yield with loss	USPAT; US-PGPUB	2004/10/30 10:31
-	35	determin\$3 with yield with loss same (semiconductor or wafer)	USPAT; US-PGPUB	2004/10/30 10:31
-	5	"6367040"	USPAT; US-PGPUB	2004/10/30 10:51
-	16	("4801869"   "5355212"   "5438527"   "5598341"   "5754432"   "5761064"   "5777901"   "5787190"   "5822218"   "5828778"   "5940300"   "5943437"   "6016562"   "6017771"   "6061814"   "6169960").PN.	USPAT	2004/10/31 09:00
-	4	("3751647"   "5544256"   "5777901"   "6265232").PN.	USPAT	2004/10/31 09:08
-	192	kill adj2 ratio	USPAT; US-PGPUB	2004/10/31 09:30
-	0	kill adj2 ratio same calibrat\$3	USPAT; US-PGPUB	2004/10/31 09:30
-	13	kill adj2 ratio and calibrat\$3	USPAT; US-PGPUB	2004/10/31 09:32
-	7	kill adj2 ratio same weight\$3	USPAT; US-PGPUB	2004/10/31 10:33
-	0	yield with impact with calibrat\$3 with factor	USPAT; US-PGPUB	2004/10/31 11:33
-	14	yield same impact same calibrat\$3 same factor	USPAT; US-PGPUB	2004/10/31 10:34
-	142	kill adj2 ratio and weight\$3	USPAT; US-PGPUB	2004/10/31 10:42
-	3	yield adj2 loss and calibration adj2 factor	USPAT; US-PGPUB	2004/10/31 10:57
-	139	defect with excursion	USPAT; US-PGPUB	2004/10/31 10:47
-	0	defect with excursion with limit	USPAT; US-PGPUB	2004/10/31 10:47
-	3	defect with excursion same calibrat\$3	USPAT; US-PGPUB	2004/10/31 10:51
-	18	defect with calibrat\$3 with factor	USPAT; US-PGPUB	2004/10/31 10:52
-	359	yield adj2 loss and calibrat\$3	USPAT; US-PGPUB	2004/10/31 10:57



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**JNL** = Journal or Magazine **CNF** = Conference **STD** = Standard**1 The impact of tolerance on kill ratio estimation for memory**

Patterson, O.D.; Hansen, M.H.;  
Semiconductor Manufacturing, IEEE Transactions on, Volume: 15, Issue: 4, Nov. 2002

Pages:404 - 410

[\[Abstract\]](#) [\[PDF Full-Text \(517 KB\)\]](#) **IEEE JNL****2 The impact of tolerance on kill ratio estimation for memory**

Patterson, O.D.; Hansen, M.H.;  
Advanced Semiconductor Manufacturing Conference and Workshop, 2000  
IEEE/SEMI, 12-14 Sept. 2000

Pages:175 - 180

[\[Abstract\]](#) [\[PDF Full-Text \(488 KB\)\]](#) **IEEE CNF****3 Critical area based yield prediction using in-line defect classification information [DRAMs]**

Segal, J.; Sagatelian, A.; Hodgkins, B.; Ben Chu; Singh, T.; Berman, H.;  
Advanced Semiconductor Manufacturing Conference and Workshop, 2000  
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Pages:83 - 88

[\[Abstract\]](#) [\[PDF Full-Text \(508 KB\)\]](#) **IEEE CNF****4 Evaluation of the yield impact of epitaxial defects on advanced semiconductor technologies**

Williams, R.; Jacques, R.; Akbulut, M.; Wayne Chen;  
Advanced Semiconductor Manufacturing Conference and Workshop, 2000  
IEEE/SEMI, 12-14 Sept. 2000

Pages:1 - 7

[\[Abstract\]](#) [\[PDF Full-Text \(528 KB\)\]](#) **IEEE CNF**

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**5 SmartBit™: bitmap to defect correlation software for yield improvement**

*Merino, M.A.; Cruceta, S.; Garcia, A.; Recio, M.;*

Advanced Semiconductor Manufacturing Conference and Workshop, 2000

IEEE/SEMI , 12-14 Sept. 2000

Pages:194 - 198

[\[Abstract\]](#) [\[PDF Full-Text \(372 KB\)\]](#) [IEEE CNF](#)

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**6 Key considerations in the development of defect sampling methodologies**

*McIntyre, M.; Nurani, R.K.; Akella, R.;*

Advanced Semiconductor Manufacturing Conference and Workshop, 1996. ASMC

96 Proceedings. IEEE/SEMI 1996 , 12-14 Nov. 1996

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[\[Abstract\]](#) [\[PDF Full-Text \(484 KB\)\]](#) [IEEE CNF](#)

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**7 Limitations to estimating yield based on in-line defect measurements**

*Riley, S.L.;*

Defect and Fault Tolerance in VLSI Systems, 1999. DFT '99. International

Symposium on , 1-3 Nov. 1999

Pages:46 - 54

[\[Abstract\]](#) [\[PDF Full-Text \(132 KB\)\]](#) [IEEE CNF](#)

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